

# RÃ©my Gassilloud

## List of Publications by Year in descending order

Source: <https://exaly.com/author-pdf/8556708/publications.pdf>

Version: 2024-02-01

6  
papers

119  
citations

1937685

4  
h-index

1872680

6  
g-index

6  
all docs

6  
docs citations

6  
times ranked

153  
citing authors

#	ARTICLE	IF	CITATIONS
1	Selective deposition of Ta <sub>2</sub> O <sub>5</sub> by adding plasma etching super-cycles in plasma enhanced atomic layer deposition steps. Journal of Vacuum Science and Technology A: Vacuum, Surfaces and Films, 2017, 35, .	2.1	50
2	Plasma depositionâ€™Impact of ions in plasma enhanced chemical vapor deposition, plasma enhanced atomic layer deposition, and applications to area selective deposition. Journal of Vacuum Science and Technology A: Vacuum, Surfaces and Films, 2020, 38, .	2.1	32
3	Area selective deposition of TiO <sub>2</sub> by intercalation of plasma etching cycles in PEALD process: A bottom up approach for the simplification of 3D integration scheme. Journal of Vacuum Science and Technology A: Vacuum, Surfaces and Films, 2019, 37, 020918.	2.1	26
4	Low temperature Topographically Selective Deposition by Plasma Enhanced Atomic Layer Deposition with ion bombardment assistance. Journal of Vacuum Science and Technology A: Vacuum, Surfaces and Films, 2021, 39, 032416.	2.1	5
5	Area selective deposition using alternate deposition and etch super-cycle strategies. Dalton Transactions, 2022, 51, 442-450.	3.3	5
6	Topographical selective deposition: A comparison between plasma-enhanced atomic layer deposition/sputtering and plasma-enhanced atomic layer deposition/quasi-atomic layer etching approaches. Journal of Vacuum Science and Technology A: Vacuum, Surfaces and Films, 2021, 39, 030402.	2.1	1